

ABSTRACT OF THE DISCLOSURE

A remote control system for one or more semiconductor manufacturing apparatuses is provided which is capable of displaying at a remote operation device the same screen as that in a host device and performing through the remote control device the same operations as those carried out by the host device. The remote operation device includes a LAN system having one or more semiconductor manufacturing apparatuses (D) and a host device (H) on the semiconductor manufacturing apparatus side, and a remote operation device (L) having a communication element (Com) accessible to the host device (H) on the semiconductor manufacturing apparatus side through a communication line. The host device (H) implements an IP routing function and a necessary protocol for achieving remote operations from the remote operation device (L), and also a communication element (Com) with a message incoming function of messages incoming from the communication line. The host device (H) performs user authentication when the remote operation device is connected to the host device, whereby it becomes possible for the remote operation device thus authenticated to display the same screen as that displayed on the host device (H) and remotely operate and control the host device (H).